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Nanomanufacturing - Reliability and durability assessment -
Part 3-2: Graphene - Ellipsometry measurement of graphene

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CONTENTS

FOREWORD ... 3
INTRODUCTION ... 5
1 Scope ... 6
2 Normative references ... 6
3 Terms, definitions, and abbreviated terms ... 6
3.1 General terms ... 6
3.2 Terms specific to this document ... 7
3.3 Abbreviated terms ... 8
4 Measurement of ellipsometry ... 8
4.1 General ... 8
4.2 Measurement procedure ... 8
4.2.1 Sample preparation for system check ... 8
4.2.2 Experimental procedure for system check ... 8
4.2.3 Sample handling ... 9
4.2.4 Experimental procedures ... 9
5 Reporting data ... 9
6 Data analysis / interpretation of results ... 9
6.1 General ... 9
6.2 Setting analysis model ... 10
6.3 Data fitting and validation of analysis result ... 10
Annex A (informative) Case study ... 11
A.1 Reliability and durability assessment of graphene ... 11
A.1.1 Sample description ... 11
A.1.2 Reliability test ... 11
A.2 Ellipsometry spectra and the parameter fitting ... 11
A.3 Results and the analysis ... 13
Annex B (informative) Case study ... 15
B.1 Reliability and durability assessment of graphene ... 15
B.1.1 Sample description ... 15
B.1.2 Reliability test ... 15
B.2 Ellipsometry spectra ... 15
B.3 Results and the analysis ... 16
Bibliography ... 18

Figure 1 – Primary structure of ellipsometry measurement ... 8
Figure A.1 – Test sample for the reliability and durability assessment ... 11
Figure A.2 – Ellipsometry spectra of Sample A1-1 ... 12
Figure A.3 – Ellipsometry spectra of Sample B1-1 ... 13
Figure B.1 – Test samples for the reliability and durability assessment ... 15
Figure B.2 – Ellipsometry spectra of SLG ... 16
Figure B.3 – Ellipsometry spectra of TLG ... 16

Table A.1 – Fitting results of sample A1-1 and B1-1 before THS test 14
Table A.2 – Fitting results of sample A1-1 and B1-1 after THS test 14
Table B.1 – Summary of spectroscopic-ellipsometry-analysis results for SLG/Cu and TLG/Cu before and after the 100 h THS test 17

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Nanomanufacturing - Reliability and durability assessment -
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Full information on the voting for its approval can be found in the report on voting indicated in the above table.

The language used for the development of this Technical Specification is English.

This document was drafted in accordance with ISO/IEC Directives, Part 2, and developed in accordance with ISO/IEC Directives, Part 1 and ISO/IEC Directives, IEC Supplement, available at www.iec.ch/members_experts/refdocs. The main document types developed by IEC are described in greater detail at www.iec.ch/publications.

A list of all parts in the IEC 62876 series, published under the general title *Nanomanufacturing - Reliability and durability assessment*, can be found on the IEC website.

The committee has decided that the contents of this document will remain unchanged until the stability date indicated on the IEC website under webstore.iec.ch in the data related to the specific document. At this date, the document will be

– reconfirmed,
– withdrawn, or
– revised.

INTRODUCTION

Graphene, a single layer of carbon atoms with each atom bound to three neighbours in a honeycomb structure, is an important building block of many carbon nano-objects, and possesses the excellent characteristics for various nanoelectronics devices, such as the high conductivity in the 2-dimensional structure. Graphene is also a promising candidate for atomically thin, flexible and transparent optoelectronic devices, various sensors, and the capping material on the electronic transport in ultra-scaled interconnects. Ellipsometry is a non-destructive optical tool to evaluate the dielectric properties, namely the complex index of refractive, of thin-film-shaped materials. Ellipsometry has the advantage of being able to evaluate a relatively large area of the film. Ellipsometry can be used to characterize thickness, roughness, composition, crystalline nature, and other properties of graphene.

This document offers the test method of ellipsometry to evaluate the reliability and the durability of graphene layers on a substrate.

1 Scope

This part of 62876 establishes a standardized method to determine

– volume fraction

for graphene by

– ellipsometry.

Thickness/composition measurements are evaluated by ellipsometry before and after the stability test. By model calculation, the volume fraction of graphene can be evaluated. Since the test method is non-destructive, it can be used to assess the reliability and durability of graphene films on production lines.

– For graphene-capped copper for Cu interconnects in a semiconductor engineering, for example, the reliability and durability of the capping layer are evaluated.
– Gas sensors, gas barriers, transparent electrodes for solar cells, etc. are being researched and developed.
– This method is useful for non-destructive and quantitative evaluation of the volume fraction of graphene to assess the reliability and durability.

2 Normative references

The following documents are referred to in the text in such a way that some or all of their content constitutes requirements of this document. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

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